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STN# Cas, Japio, Inspec

(FILE 'HOME' ENTERED AT 13:52:33 ON 16 NOV 2001)

FILE 'CA' ENTERED AT 13:52:42 ON 16 NOV 2001

L1 233 S (CMP OR POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR GRIND?
L2 1 S L1 AND (TI2O3 OR CE2O3 OR TITANIA# OR CERIA# OR TI(5W)O OR CE
L3 232 S L1 NOT L2
L4 14 S L3 AND (ABRASSIVE? OR METAL?(3A)OXID? OR SILICA# OR ALUMINA#
L5 4 S L3 AND (ABRAS? OR DIAMOND OR CARBID? OR ZR(8W)O OR AL(8W)O OR
L6 15 S L4 OR L5
L7 15 S L1 AND (SIO OR SIO2 OR OXIDE? OR ?SILICAT? OR SOG OR GLASS? O
L8 0 S L1 AND (PHOSPHOBORO? OR BOROPHOSPHO? OR PHOSPHOSI? OR BOROSI?
L9 1 S L1 AND (SI3N4 OR NITRID? OR SI(8W)N)
L10 5 S L6 AND (L7 OR L8 OR L9)
L11 15 S L10 OR L6
L12 165 S L1 AND (HNO3 OR ACID OR BASE OR PH OR NH4OH OR R4NOH OR KOH O
L13 10 S L11 AND L12
L14 15 S L11 OR L13
L15 16 S L2 OR L14

FILE 'JAPIO' ENTERED AT 14:00:41 ON 16 NOV 2001

L16 0 S L15

FILE 'INSPEC' ENTERED AT 14:01:42 ON 16 NOV 2001

L17 0 S L15

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TSN: Cas, Japio

(FILE 'USPATFULL' ENTERED AT 15:25:44 ON 16 NOV 2001)
DEL HIS

FILE 'CA' ENTERED AT 15:29:33 ON 16 NOV 2001

L1 4570 S (CMP OR POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR GRIND?
L2 637 S L1 AND ALPHA
L3 871 S (CMP OR POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR GRIND?
L4 1400 S L2 OR L3
L5 4803 S L1 OR L4
L6 74 S L5 AND (SEMICONDUCT? OR WAFER# OR CHIP#)
L7 4729 S L5 NOT L6
L8 562 S L7 AND (CMP OR POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR
L9 213 S L8 AND POLISH?/TI

FILE 'JAPIO' ENTERED AT 15:48:32 ON 16 NOV 2001

L10 9 S L6
L11 16 S L9

FILE 'CA' ENTERED AT 15:51:18 ON 16 NOV 2001

L12 349 S L8 NOT L9

FILE 'JAPIO' ENTERED AT 15:51:27 ON 16 NOV 2001

L13 29 S L12

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STN:USPAT

(FILE 'HOME' ENTERED AT 14:30:17 ON 16 NOV 2001)

FILE 'USPATFULL' ENTERED AT 14:32:28 ON 16 NOV 2001

L1 317 S (ALPHA(3W)?AMINO?) (P) (CMP OR ?POLISH? OR CHEMIMECH? OR PLANAR
L2 206 S L1(P) (ACID OR CARBOX?)
SET HIGH OFF
L3 8 S L2 AND (WAFER# OR CHIP# OR SEMICONDUCT?)
SET HIGH ON
L4 8 S L2 AND L3
L5 198 S L2 NOT L4

FILE 'USPATFULL' ENTERED AT 14:36:08 ON 16 NOV 2001

L6 198 S L2 NOT L4
SET HIGH OFF
L7 0 S L6 AND (SEMICONDUCT? OR WAFER# OR CHIP#)
SET HIGH ON
L8 147129 S ?AMINO?(10A)ACID
L9 3059 S L8(P) (CMP OR ?POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR G
SET HIGH OFF
L10 272 S L9 AND (SEMICONDUCT? OR WAFER# OR CHIP#)
SET HIGH ON
L11 272 S L9 AND L10
L12 301 S L9(P)ALPHA
L13 11 S L12 AND L11
L14 261 S L11 NOT L13
L15 40 S L14 AND (CMP OR ?POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? O
L16 221 S L14 NOT L15
L17 1212 S (PROLINE? OR GLYCINE? OR ALANINE? OR ARGININE? OR LYSINE?) (P)
SET HIGH OFF
L18 85 S L17 AND (SEMICONDUCT? OR WAFER# OR CHIP#)
SET HIGH ON
L19 85 S L17 AND L18
L20 1127 S L17 NOT L19
L21 1085 S L20 NOT (L14 OR L2)
L22 0 S L19 AND L21
L23 1085 S L20 AND L21
L24 12 S L23 AND (CMP OR ABRAS? OR ?POLISH? OR CHEMIMECH? OR PLANARIZ?
L25 1073 S L23 NOT L24
L26 575 S L17(P)ACID
L27 220 S L17(P)ALPHA
L28 110 S L26 AND L27 AND L25
L29 535 S (L26 OR L27) NOT L28
L30 2 S L29 AND MANUFACT?/TI
L31 533 S L29 NOT L30
L32 627 S L25 NOT L29
SAVE POLISHL32/A L32

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STN & USPAT

(FILE 'USPATFULL' ENTERED AT 14:03:47 ON 16 NOV 2001)

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L1 59 S (CMP OR POLISH? OR CHEMIMECH? OR PLANARIZ? OR LAP? OR GRIND?
L2 0 S L1(P) (TI2O3 OR CE2O3 OR TITANIA# OR CERIA# OR TI(5W)O OR CE(5
L3 1 S L1(P) (ABRASSIVE? OR METAL? (3A)OXID? OR SILICA# OR ALUMINA# OR
L4 0 S L1(P) (ABRAS? OR DIAMOND OR CARBID? OR ZR(8W)O OR AL(8W)O OR S
L5 0 S L1(P) (PHOSPHOBORO? OR BOROPHOSPHO? OR PHOSPHOSI? OR BOROSI?)
L6 1 S L1(P) (SIO OR SIO2 OR OXIDE? OR ?SILICAT? OR SOG OR GLASS? OR
L7 0 S L1(P) (SI3N4 OR NITRID? OR SI(8W)N)
L8 30 S L1(P) (HNO# OR ACID OR BASE OR PH OR NH4OH OR R4NOH OR KOH OR
L9 59 S L1 OR L3 OR L6 OR L8
L10 1 S (L3 OR L6) AND L9
L11 58 S L1 NOT L10
L12 58 S L9 AND L11
SET HIGH OFF
L13 13 S L12 AND (SEMICONDUCT? OR WAFER? OR CHIP?)
SET HIGH ON
L14 13 S L12 AND L13
L15 45 S L12 NOT L14
L16 128 S SLURR?(P) (PROLINE?)
SET HIGH OFF
L17 5 S L16 AND (SEMICONDUCT? OR WAFER? OR CHIP?)
SET HIGH ON
L18 5 S L16 AND L17
L19 123 S L16 NOT L18
L20 5 S L18 NOT L1
L21 123 S L19 NOT L1

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